

**200mm Dynamic Wafer Slide Transfer**

*The GLA wafer slide transfer systems provide safe and quick transfer of wafers. At various stages of FAB process functions, wafer transfer from cassette to cassette is required. GLA offers two production-proven hand operated wafer transfer models to reliably meet these requirements in a cost-effective manner. The wafer transfer models are manufactured from SEMI approved materials minimizing or eliminating any possibility of particle generation.*

Two models of transfer systems are available – Dynamic and Standard Wafer Slide Transfers.

The compact Dynamic slide transfer model supports the sending and receiving cassettes on a moving platform virtually eliminating particle generation. The moving platform will not move until receiving cassette is in position and releases the safety lock. This design has a very small footprint and is easy to use.

The low cost Standard slide transfer model supports the cassettes on an ultra-low friction, low particle slide surface. The cassettes are gently pushed to transfer wafers.

## Product Specifications

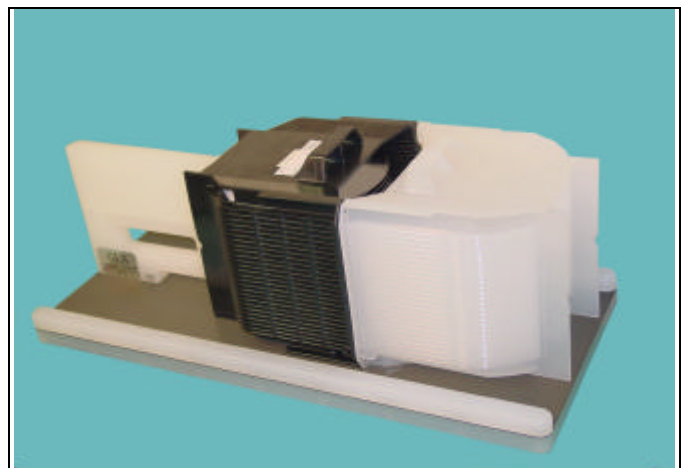
Wafer Size	Model No.	Footprint (mm)
<b>Standard</b>		
100mm	ST4	355 × 180
150mm	ST6	558 × 235
200mm	ST8	660 × 292
<b>Dynamic</b>		
100mm	STD-4P	373 × 133
150mm	STD-6P	483 × 152
200mm	STD-8P	683 × 190

## Key Features

- Low particle generation materials to provide Class 1 cleanliness
- Special materials such as Ultem for high temperature requirements
- ESD models available

## Options

- Cassette Combinations: 200-150mm; 150-125mm
- Cassette Types: STD, Metal, or Reduced height
- Slide Surface on Standard Transfers
- Full Cassette or Partial Cassette Transfers
- Custom designs for unique cassette combinations



**200mm Standard Wafer Slide Transfer**

